

FORM PTO-1449  
(REV. 6-89)U.S. DEPARTMENT OF COMMERCE  
Patent and Trademark OfficeAttorney's Docket No.  
3154Serial No.  
08/984,558

## INFORMATION DISCLOSURE CITATION

MAR 23 1998

(Use several sheets if necessary)

Applicants

David Alumot, et al.

Filing Date  
12/03/97Group Art Unit 2721  
Unassigned

## U.S. PATENT DOCUMENTS

| Examiner Initials | Document Number  | Date     | Name              | Class | Subclass   | Filing Date If Appropriate |
|-------------------|------------------|----------|-------------------|-------|------------|----------------------------|
| AN                | 5 6 9 9 4 4 7    | 12/16/97 | Alumot, et al.    | 382   | 145        | RECEIVED                   |
| AN                | 4 7 4 0 7 0 8    | 04/26/88 | Batchelder        | 250   | 563        | FEB 09 1999                |
| AN                | ** 4 5 8 9 1 4 0 | 05/86    | Bishop, et al.    | 382   | 8          |                            |
| AN                | ** 5 1 3 3 6 0 1 | 07/92    | Cohen, et al.     | 356   | GROUP 2700 |                            |
| AN                | ** 4 9 2 6 4 8 9 | 05/90    | Danielson, et al. | 382   | 8          |                            |
| AN                | 4 4 4 1 1 2 4    | 04/03/84 | Heebner, et al.   | 358   | 106        |                            |
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## FOREIGN PATENT DOCUMENTS

|  | Document Number | Date | Country | Class | Subclass | Translation                                                         |
|--|-----------------|------|---------|-------|----------|---------------------------------------------------------------------|
|  |                 |      |         |       |          | Yes <input checked="" type="checkbox"/> No <input type="checkbox"/> |
|  |                 |      |         |       |          | AN 8:35                                                             |
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|----------|-------------------------------------|-----------------|-------------|
| EXAMINER | ANDREW W. JOHNS<br>PRIMARY EXAMINER | DATE CONSIDERED | MAR 24 1999 |
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